## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L4	6390	118/723\$.ccls. 156/345\$.ccls.	USPAT	OR	ON	2009/01/29 12:23
L5	77609	(computer control\$4) with ((lift\$3 vertical adjust\$3 mov\$4 elevat\$3 push\$3) with (object substrate wafer electrode cathode anode))	USPAT	OR	ON	2009/01/29 12:23
L6	906	4 and L5	USPAT	OR	ON	2009/01/29 12:23
L7	1205	(118/723e).CCLS.	USPAT	OR	OFF	2009/01/29 12:25
L8	755	((156/345.43) or (156/345.44) or (156/345.45) or (156/345.46) or (156/345.47)).CCLS.	USPAT	OR	OFF	2009/01/29 12:25
L9	1613	L7 L8	USPAT	OR	OFF	2009/01/29 12:25
L10	263	L5 and L9	USPAT	OR	OFF	2009/01/29 12:25
L11	643	6 not L10	USPAT	OR	ON	2009/01/29 12:25
S100	13630	(plasma with (ignit\$4 generat\$4 form\$6)) same (lift\$3 vertical adjust\$3 mov\$4 elevat\$3 push\$3)	USPAT	OR	ON	2009/01/26 17:46
S101	6381	118/723\$.ccls. 156/345\$.ccls.	USPAT	OR	ON	2009/01/26 17:47
S102	1822	S100 and S101	USPAT	OR	ON	2009/01/26 17:47
S103	736	(plasma with ignit\$4) same (lift\$3 vertical adjust\$3 mov\$4 elevat\$3 push\$3)	USPAT	OR	ON	2009/01/26 17:48
S104	177	S103 and S101	USPAT	OR	ON	2009/01/26 17:48

S105	75	(plasma with ignit\$4) same ((lift\$3 vertical adjust\$3 mov\$4 elevat\$3 push\$3) with (object substrate wafer electrode cathode anode))	JPO; DERWENT	OR	ON	2009/01/26 19:29
S106	1727	(plasma with generat \$4) same ((lift\$3 vertical adjust\$3 mov \$4 elevat\$3 push\$3) with (object substrate wafer electrode cathode anode))	JPO; DERWENT	OR	ON	2009/01/26 19:59
S107	419895	h01l021\$.ipc. c23c016 \$.ipc.	JPO; DERWENT	OR	ON	2009/01/26 20:15
S109	3	"10302998"	JPO; DERWENT	OR	ON	2009/01/26 20:16
S110	5	"10112276"	JPO; DERWENT	OR	ON	2009/01/26 20:16
S111	2	(("5110437") or ("5423936")).PN.	USPAT; USOCR	OR	OFF	2009/01/26 20:18
S112	135	(156/345.54).CCLS.	USPAT; USOCR	OR	OFF	2009/01/27 13:23
S113	800	(118/729).CCLS.	USPAT; USOCR	OR	OFF	2009/01/27 13:23
S114	800	(118/729).CCLS.	USPAT; USOCR	OR	OFF	2009/01/27 17:46
S115	275	S114 and (electrode cathode anode)	USPAT	OR	ON	2009/01/27 17:46
S116	135	(156/345.54).CCLS.	USPAT; USOCR	OR	OFF	2009/01/27 17:52
S117	250	S115 not S116	USPAT	OR	ON	2009/01/27 17:52
S118	1727	(plasma with generat \$4) same ((lift\$3 vertical adjust\$3 mov \$4 elevat\$3 push\$3) with (object substrate wafer electrode cathode anode))	JPO; DERWENT	OR	ON	2009/01/27 18:58
S119	419895	h01l021\$.ipc. c23c016 \$.ipc.	JPO; DERWENT	OR	ON	2009/01/27 18:58
S120	633	S118 and S119	JPO; DERWENT	OR	ON	2009/01/27 18:58

1/29/2009 2:21:45 PM

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